
Semiconductor devices - Mechanical and climatic test methods - Part 10:
Mechanical shock (IEC 60749-10:2002)

iTeh STANDARD PREVIEW
(standards.iteh.ai)

[SIST EN 60749-10:2004](https://standards.iteh.ai/catalog/standards/sist/3a6d37ce-0949-4efd-8938-89fb4b4d4e32/sist-en-60749-10-2004)
[https://standards.iteh.ai/catalog/standards/sist/3a6d37ce-0949-4efd-8938-
89fb4b4d4e32/sist-en-60749-10-2004](https://standards.iteh.ai/catalog/standards/sist/3a6d37ce-0949-4efd-8938-89fb4b4d4e32/sist-en-60749-10-2004)

iTeh STANDARD PREVIEW
(standards.iteh.ai)

SIST EN 60749-10:2004

<https://standards.iteh.ai/catalog/standards/sist/3a6d37ce-0949-4efd-8938-89fb4b4d4e32/sist-en-60749-10-2004>

EUROPEAN STANDARD

EN 60749-10

NORME EUROPÉENNE

EUROPÄISCHE NORM

August 2002

ICS 31.080.01

Partly supersedes EN 60749:1999 + A1:2000 + A2:2001

English version

**Semiconductor devices -
Mechanical and climatic test methods
Part 10: Mechanical shock
(IEC 60749-10:2002)**

Dispositifs à semiconducteurs -
Méthodes d'essais mécaniques
et climatiques
Partie 10: Chocs mécaniques
(CEI 60749-10:2002)

Halbleiterbauelemente -
Mechanische und klimatische
Prüfverfahren
Teil 10: Mechanisches Schocken
(IEC 60749-10:2002)

iTeh STANDARD PREVIEW
(standards.iteh.ai)

[SIST EN 60749-10:2004](https://standards.iteh.ai/catalog/standards/sist/3a6d37ce-0949-4efd-8938-324444444444/sist-60749-10-2002)

<https://standards.iteh.ai/catalog/standards/sist/3a6d37ce-0949-4efd-8938-324444444444/sist-60749-10-2002>
This European Standard was approved by CENELEC on 2002-07-02. CENELEC members are bound to comply with the CEN/CENELEC Internal Regulations which stipulate the conditions for giving this European Standard the status of a national standard without any alteration.

Up-to-date lists and bibliographical references concerning such national standards may be obtained on application to the Central Secretariat or to any CENELEC member.

This European Standard exists in three official versions (English, French, German). A version in any other language made by translation under the responsibility of a CENELEC member into its own language and notified to the Central Secretariat has the same status as the official versions.

CENELEC members are the national electrotechnical committees of Austria, Belgium, Czech Republic, Denmark, Finland, France, Germany, Greece, Hungary, Iceland, Ireland, Italy, Luxembourg, Malta, Netherlands, Norway, Portugal, Slovakia, Spain, Sweden, Switzerland and United Kingdom.

CENELEC

European Committee for Electrotechnical Standardization
Comité Européen de Normalisation Electrotechnique
Europäisches Komitee für Elektrotechnische Normung

Central Secretariat: rue de Stassart 35, B - 1050 Brussels

Foreword

The text of document 47/1598/FDIS, future edition 1 of IEC 60749-10, prepared by IEC TC 47, Semiconductor devices, was submitted to the IEC-CENELEC parallel vote and was approved by CENELEC as EN 60749-10 on 2002-07-02.

This mechanical and climatic test method, as it relates to mechanical shock, is a complete rewrite of the test contained in clause 4, chapter 2 of EN 60749:1999.

The following dates were fixed:

- latest date by which the EN has to be implemented at national level by publication of an identical national standard or by endorsement (dop) 2003-04-01
- latest date by which the national standards conflicting with the EN have to be withdrawn (dow) 2005-07-01

Annexes designated "normative" are part of the body of the standard.
In this standard, annex ZA is normative.
Annex ZA has been added by CENELEC.

Endorsement notice

The text of the International Standard IEC 60749-10:2002 was approved by CENELEC as a European Standard without any modification.

(standards.iteh.ai)

[SIST EN 60749-10:2004](https://standards.iteh.ai/catalog/standards/sist/3a6d37ce-0949-4efd-8938-89fb4b4d4e32/sist-en-60749-10-2004)

<https://standards.iteh.ai/catalog/standards/sist/3a6d37ce-0949-4efd-8938-89fb4b4d4e32/sist-en-60749-10-2004>

Annex ZA
(normative)

**Normative references to international publications
with their corresponding European publications**

This European Standard incorporates by dated or undated reference, provisions from other publications. These normative references are cited at the appropriate places in the text and the publications are listed hereafter. For dated references, subsequent amendments to or revisions of any of these publications apply to this European Standard only when incorporated in it by amendment or revision. For undated references the latest edition of the publication referred to applies (including amendments).

NOTE When an international publication has been modified by common modifications, indicated by (mod), the relevant EN/HD applies.

<u>Publication</u>	<u>Year</u>	<u>Title</u>	<u>EN/HD</u>	<u>Year</u>
IEC 60068-2-27	1987	Basic environmental testing procedures Part 2: Tests - Test Ea and guidance: Shock	EN 60068-2-27	1993

iTeh STANDARD PREVIEW
(standards.iteh.ai)

[SIST EN 60749-10:2004](#)

<https://standards.iteh.ai/catalog/standards/sist/3a6d37ce-0949-4efd-8938-89fb4b4d4e32/sist-en-60749-10-2004>

iTeh STANDARD PREVIEW
(standards.iteh.ai)

SIST EN 60749-10:2004

<https://standards.iteh.ai/catalog/standards/sist/3a6d37ce-0949-4efd-8938-89fb4b4d4e32/sist-en-60749-10-2004>

NORME
INTERNATIONALE
INTERNATIONAL
STANDARD

CEI
IEC

60749-10

Première édition
First edition
2002-04

**Dispositifs à semiconducteurs –
Méthodes d'essais mécaniques et climatiques –**

**Partie 10:
Chocs mécaniques**

iTeh STANDARD PREVIEW

**Semiconductor devices –
Mechanical and climatic test methods –**

SIST EN 60749-10:2004

[https://standards.iTech.ai/catalog/standards/sist/3a6d37ce-0949-4efd-8938-](https://standards.iTech.ai/catalog/standards/sist/3a6d37ce-0949-4efd-8938-89fb4b4d4e32/sist-en-60749-10-2004)

**Part 10:
Mechanical shock**

© IEC 2002 Droits de reproduction réservés — Copyright - all rights reserved

Aucune partie de cette publication ne peut être reproduite ni utilisée sous quelque forme que ce soit et par aucun procédé, électronique ou mécanique, y compris la photocopie et les microfilms, sans l'accord écrit de l'éditeur.

No part of this publication may be reproduced or utilized in any form or by any means, electronic or mechanical, including photocopying and microfilm, without permission in writing from the publisher.

International Electrotechnical Commission, 3, rue de Varembe, PO Box 131, CH-1211 Geneva 20, Switzerland
Telephone: +41 22 919 02 11 Telefax: +41 22 919 03 00 E-mail: inmail@iec.ch Web: www.iec.ch



Commission Electrotechnique Internationale
International Electrotechnical Commission
Международная Электротехническая Комиссия

CODE PRIX
PRICE CODE

D

*Pour prix, voir catalogue en vigueur
For price, see current catalogue*

INTERNATIONAL ELECTROTECHNICAL COMMISSION

**SEMICONDUCTOR DEVICES –
MECHANICAL AND CLIMATIC TEST METHODS –**

Part 10: Mechanical shock

FOREWORD

- 1) The IEC (International Electrotechnical Commission) is a worldwide organization for standardization comprising all national electrotechnical committees (IEC National Committees). The object of the IEC is to promote international co-operation on all questions concerning standardization in the electrical and electronic fields. To this end and in addition to other activities, the IEC publishes International Standards. Their preparation is entrusted to technical committees; any IEC National Committee interested in the subject dealt with may participate in this preparatory work. International, governmental and non-governmental organizations liaising with the IEC also participate in this preparation. The IEC collaborates closely with the International Organization for Standardization (ISO) in accordance with conditions determined by agreement between the two organizations.
- 2) The formal decisions or agreements of the IEC on technical matters express, as nearly as possible, an international consensus of opinion on the relevant subjects since each technical committee has representation from all interested National Committees.
- 3) The documents produced have the form of recommendations for international use and are published in the form of standards, technical specifications, technical reports or guides and they are accepted by the National Committees in that sense.
- 4) In order to promote international unification, IEC National Committees undertake to apply IEC International Standards transparently to the maximum extent possible in their national and regional standards. Any divergence between the IEC Standard and the corresponding national or regional standard shall be clearly indicated in the latter.
- 5) The IEC provides no marking procedure to indicate its approval and cannot be rendered responsible for any equipment declared to be in conformity with one of its standards.
- 6) Attention is drawn to the possibility that some of the elements of this International Standard may be the subject of patent rights. The IEC shall not be held responsible for identifying any or all such patent rights.

International Standard IEC 60749-10 has been prepared by IEC technical committee 47: Semiconductor devices.

The text of this standard is based on the following documents:

FDIS	Report on voting
47/1598/FDIS	47/1613/RVD

Full information on the voting for the approval of this standard can be found in the report on voting indicated in the above table.

This mechanical and climatic test method, as it relates to mechanical shock, is a complete rewrite of the test contained in clause 4, chapter 2 of IEC 60749.

This publication has been drafted in accordance with the ISO/IEC Directives, Part 3.

The committee has decided that the contents of this publication will remain unchanged until 2007. At this date, the publication will be

- reconfirmed;
- withdrawn;
- replaced by a revised edition, or
- amended.

The contents of the corrigendum of August 2003 have been included in this copy.

SEMICONDUCTOR DEVICES – MECHANICAL AND CLIMATIC TEST METHODS –

Part 10: Mechanical shock

1 Scope

This part of IEC 60749 describes a shock test intended to determine the suitability of component parts for use in electronic equipment which may be subjected to moderately severe shocks as a result of suddenly applied forces or abrupt changes in motion produced by rough handling, transportation, or field operation. Shock of this type may disturb operating characteristics, particularly if the shock pulses are repetitive. This is a destructive test. It is normally applicable to cavity-type packages.

In general, this mechanical shock test is in conformity with IEC 60068-2-27 but, due to specific requirements of semiconductors, the clauses of this standard apply.

2 Normative references

The following referenced documents are indispensable for the application of this document. For dated references, only the edition cited applies. For undated references, the latest edition of the referenced document (including any amendments) applies.

IEC 60068-2-27:1987, *Environmental testing. Part 2: Tests – Test Ea and guidance: Shock*

3 Test apparatus

[SIST EN 60749-10:2004
https://standards.iteh.ai/catalog/standards/sist/3a6d37ce-0949-4efd-8938-89fb4b4d4e32/sist-en-60749-10-2004](https://standards.iteh.ai/catalog/standards/sist/3a6d37ce-0949-4efd-8938-89fb4b4d4e32/sist-en-60749-10-2004)

The shock testing apparatus shall be capable of providing shock pulses of 5 000 m/s² and 15 000 m/s² (peak) with a pulse duration between 0,5 ms and 1,0 ms to the body of the device. The acceleration pulse as determined from the unfiltered output of a transducer with natural frequency greater than or equal to five times the frequency of the shock pulse being established shall be a half-sine waveform with an allowable distortion not greater than ±20 % of the specified peak acceleration. The pulse duration shall be measured between the points at 10 % of the peak acceleration during rise time and 10 % of the peak acceleration during decay time. Absolute tolerances of the pulse duration shall be ±30 % of the specified duration.

4 Procedure

The shock testing apparatus shall be mounted on a sturdy laboratory table or equivalent base and levelled before use. The device shall be rigidly mounted or restrained by its case with suitable protection for the leads. Means may be provided to prevent the shock from being repeated due to "bounce" in the apparatus. Unless otherwise specified, the device shall be subject to five shock pulses of the peak level (*g*) specified in the selected test condition and for the pulse duration specified in each of the orientations X_1 , X_2 , Y_1 , Y_2 , Z_1 , and Z_2 . One required orientation (Y_1) shall be defined as that one in which the internal element(s) tends to be removed from its mount. Unless otherwise specified, test condition B shall apply.